Run Sheet for Wet Oxidation

Sample ID	Temp	Time	Ramp Rate	Notes: (sample location/orientation, wafer type, final color, etc.)

Run Sheet for Dry Oxidation

Sample ID	Temp	Time	Ramp Rate	Gas Type & Flow rate	Notes: (sample location/orientation, wafer type, final color, etc.)

Run Sheet for Spin-on Dopant and Diffusion Furnace

Sample ID	Dopant type	Spin-speed	Temp	Time	Ramp Rate	Gas Type & Flow rate	Sheet Resistance	Manufacturer est. sheet resistance	Notes: (sample location/orientation, wafer type, location of resistance measurement, etc.)

Run Sheet for Spin Coating Photoresist

Sample ID	Spin-speed	Ramp Rate	Time	Manufacturer Est. Thickness	Thickness by Profilometry	Thickness by Ellipsometry	Notes: (Uniform coverage, clean?, stayed on chuck, etc.)

Run Sheet for Ellipsometer

Sample ID	Two-wave measurements			Two-angle measurements				Schematic of measurement locations
	wave 1/wave 2	thickness	index	50 deg	70 deg	wavelength	index	

Run Sheet for Exposure & Developing Times

Sample ID	PR Spin-speed	Est. thickness	Exposure Time	Develop Time	Notes: (good patterning?, Sharp features, under-/overdeveloped, pinholes?, etc.)

Run Sheet for RIE

Sample ID	Power	Base Pressure	Gas flow rate & pressure	Etch time	Thickness etched	Etch rate	Notes:

Run Sheet for Profilometry

Sample ID	stylus force	scan length	scan speed	Step height thickness	location of scan	Notes: